diameter is ranging from 0.1 mm to 1 mm in this embodiment. In contrary, the plurality of air knives and the photolithographic mask is spaced at 0.5 mm to 3 mm at minimum and the air knives and the photolithographic mask is 20° in accordance with the conventional purge device. Moreover, the outlet of each air knife is 150 mm long and 0.5 mm gap. In the following table, result 1 to result 5 represent the data of the purge device having micronozzles in this embodiment and result 6 to result 10 represent the data of the conventional purge device. According to the table, the purge device having micronozzles in accordance with the present invention shows better PREs in large particles, medium particles, and small particles when compared with the conventional purge device.

Particle / Result	Diameter of nozzle or gap of air knife (mm)	Angle (degree)	Large Particles (Diameter > 54 μm)			Medium Particles (Diameter = 44-54 μm)			Small Particles (Diameter = 10-44 μm)		
			Count (Before)	Count (After)	PRE (%)	Count (Before)	Count (After)	PRE (%)	Count (Before)	Count (After)	PRE (%)
1	0.1	20	1	0	100.0	1	0	100.0	107	73	31.8
2	0.3	20	6	0	100.0	1	0	100.0	274	2	99.3
3	1	15	1	0	100.0	2	0	100.0	23	0	100.0
4	1	25	2	0	100.0	1	0	100.0	179	99	44.7
5	3	20	18	0	100.0	4	0	100.0	178	98	44.9
			Avg. PRE		100.0	Avg. PRE		100.0	Avg. PRE		64.1
6	0.5	20	19	0	100.0	11	6	45.5	294	128	56.5
7	0.5	20	5	1	80.0	5	2	60.0	140	134	4.3
8	0.5	20	25	2	92.0	14	3	78.6	227	164	27.8
9	0.5	20	2	1	50.0	2	1	50.0	220	159	27.7
10	0.5	20	13	3	76.9	12	4	66.7	256	204	20.3125
			Avg. PRE		79.8	Avg. PRE		60.1	Avg. PRE		27.3

[0036] At least one embodiment of the present invention provides the purge device having micronozzles and the operating method thereof. The purge device having micronozzles improves the purging efficiency and protects the pellicle from being damaged by manipulating the relative movement between the rotation

What is claimed is:

1. A purge device having micronozzles, comprising:

a base;

at least one track configured on the base;

a rotation platform configured on the base; and

a micronozzle array connected with the at least one track, wherein the micronozzle array comprises an air duct and a plurality of nozzles, and wherein the air duct is connected with the nozzles, and wherein an angle between the micronozzle array and the rotation platform is between 15° and 25°.

2. The purge device having micronozzles as claimed in claim **1**, wherein the rotation platform is embedded in the base.

~~**3**. The purge device having micronozzles as claimed in claim **1**, wherein an angle between the micronozzle array and the rotation platform is between 15° and 25°.~~

~~4~~**3**. The purge device having micronozzles as claimed in claim **1**, wherein an aperture diameter of each nozzle is between 0.3 mm and 3 mm.

~~5~~**4**. An operating method of the purge device having micronozzles as claimed in claim **1**, comprising:

placing a subject on the rotation platform;

rotating the rotation platform; and

activating the micronozzle array and sliding the micronozzle array along the at least one track to purge the subject.

~~6~~**5**. A purge device having micronozzles, comprising:

a base;

at least one track configured on the base;

a rotation platform connected with the at least one track; and

a micronozzle array configured on the base, wherein the micronozzle array

comprises an air duct and a plurality of nozzles, and wherein the air duct is connected with the nozzles, and wherein an angle between the micronozzle array and the rotation platform is between 15° and 25°.

~~7~~6. The purge device having micronozzles as claimed in claim ~~6~~5, wherein the rotation platform is embedded in the base.

~~8. The purge device having micronozzles as claimed in claim 6, wherein an angle between the micronozzle array and the rotation platform is between 15° and 25°.~~

~~9~~7. The purge device having micronozzles as claimed in claim ~~6~~5, wherein an aperture diameter of each nozzle is between 0.3 mm and 3 mm.

~~10~~8. An operating method of the purge device having micronozzles as claimed in claim ~~6~~5, comprising:

placing a subject on the rotation platform;

rotating the rotation platform and sliding the rotation platform along the at least one track; and

activating the micronozzle array to purge the subject.

~~11~~9. A purge device having micronozzles, comprising:

a base;

at least one track configured on the base;

a rotation platform connected with the at least one track; and

a micronozzle array connected with the at least one track, wherein the micronozzle array comprises an air duct and a plurality of nozzles, and wherein the air duct is connected with the nozzles, and wherein an angle between the micronozzle array and the rotation platform is between 15° and 25°.

~~12~~10. The purge device having micronozzles as claimed in claim ~~11~~9, wherein the rotation platform is embedded in the base.

~~13. The purge device having micronozzles as claimed in claim 11, wherein an~~

~~angle between the micronozzle array and the rotation platform is between 15° and 25°.~~

~~14~~11. The purge device having micronozzles as claimed in claim ~~11~~9, wherein an aperture diameter of each nozzle is between 0.3 mm and 3 mm.

~~15~~12. An operating method of the purge device having micronozzles as claimed in claim ~~11~~9, comprising:

placing a subject on the rotation platform;

rotating the rotation platform and sliding the rotation platform along the at least one track; and

activating the micronozzle array and sliding the micronozzle array along the at least one track to purge the subject.